

# **ESRF** | The European Synchrotron



# The New ID11 Nanoscope end-station A Nano-Tomography Scanner

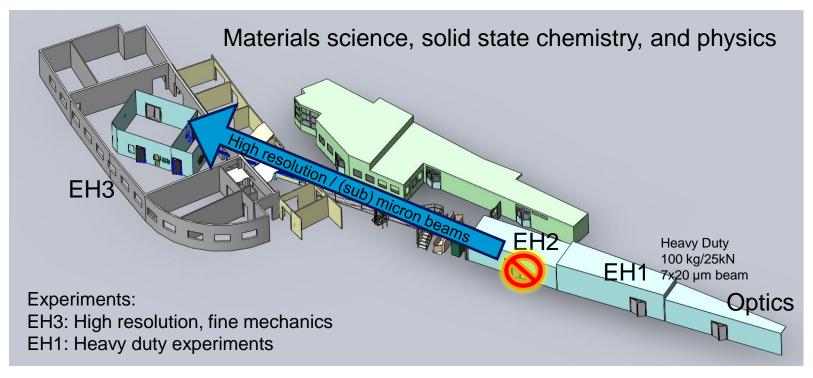
A focus on the sample positioning stages

- I. ID11 Beamline
- II. Design architecture
- III. A rotation stage with nanometer-level performance together with an electrical slip-ring
- IV. A specific high precision linear stage
- V. Conclusion and perspectives





## I. ID11 OVERVIEW

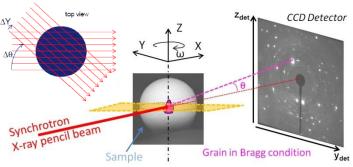


#### <u>Imaging techniques on the Nanoscope:</u>

Nano X-Ray Diffraction Computed Tomography (XRD-CT) Diffraction Contrast Tomography (rotation of a 3D sample) Fluo tomography (combination of scan and rotation)

#### X rays

Energy from 18 to 65 keV Final focalisation by a set of Nano Focusing Lenses Typical focal spot size ~100nm

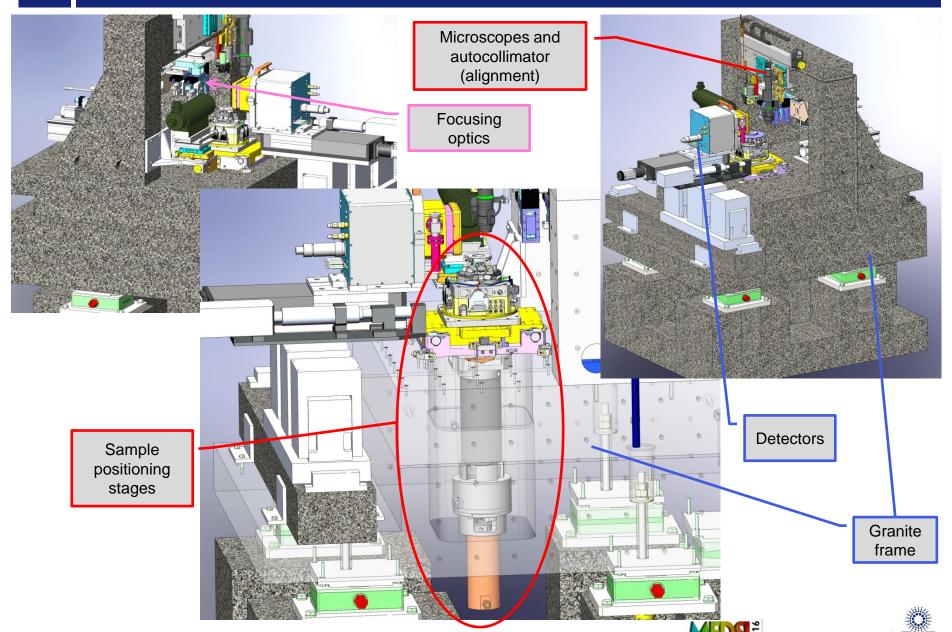


XRD-CT technique – Continuous scan in  $\omega$  and incremental positions of the Y-axis

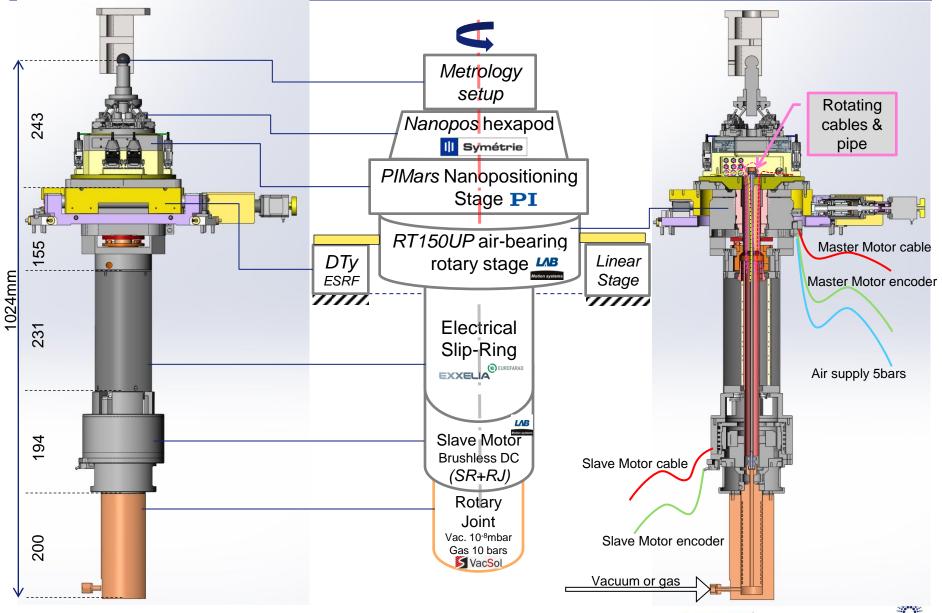




## II. Design architecture - Nanoscope end-station

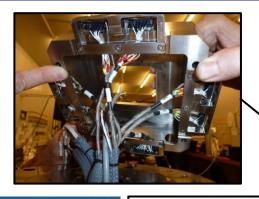


## Design architecture - Nanoscope - sample positioning stages





## III. Design architecture - Rotation stage and slip ring



Cable box

Air bearing

Max. axial load Max. radial load Air consumption <20 NI/min Total mass 15.2 Stainless stee Material



NO mechanical coupling between the slave and the master rotor (except the stiffness of the cables)

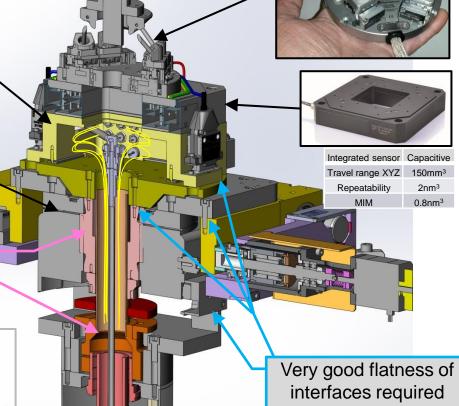
#### Slip-ring:

Standard ball-bearings

Resistive torque < 1Nm

101 electrical ways for:

- -Capacitive probes 30kHz (PIMars)
- -Piezo actuators -30/135V (PIMars)
- -Piezo motors ±48V 10kHz (Nanopos)
- -RS422 encoder signals 1MHz (Nanopos)
- -15 auxiliary signals



Travel range

Repeatability

Resolution



± 5 mm / ± 10

± 100 nm / ± 2 µrad

10 nm / 1 µrad

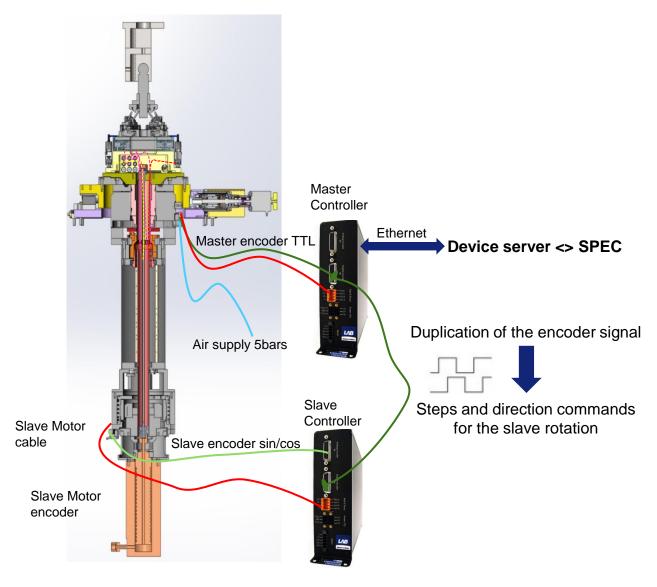
150mm<sup>3</sup>

2nm<sup>3</sup>

 $0.8 nm^{3}$ 

[1-5] µm

## III. Control Architecture - Rotation stage



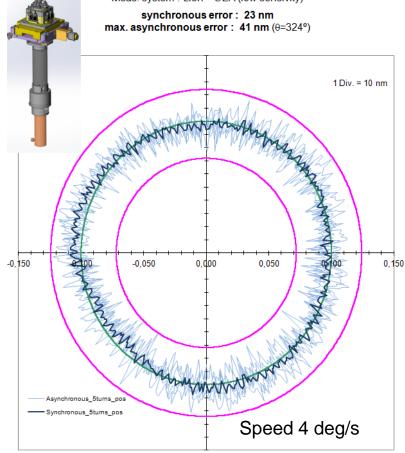


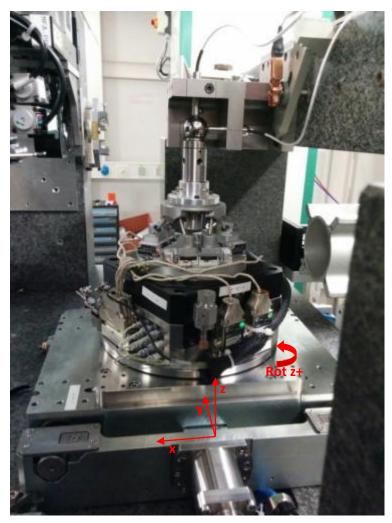
## III. Rotary stage – Metrology in BL working conditions

#### Rotary stage RT150up ID11 nanoscope Axial Error

Reference Sphere: Single diam. = 25.4 mm h = 242mm (from the top face) 5 forward of 5 full rotation (0 to 360 deg) - Meas. interval: 0,72 deg continuous motion mode, after warm-up, without drift correct. (500 points / turn - averaging 200 points @ 50kHz)

Date of measurement: 23/08/2016 - Operator : LD Meas. system : Lion + SEA (low sensivity)





All sample stages activated in closed-loop Dty-Rotation-PIMars-Nanopos





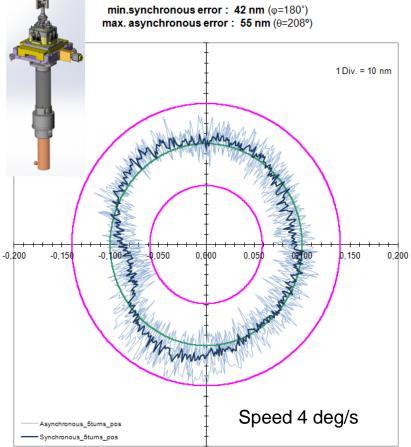
## III. Rotary stage – Metrology in BL working conditions

#### Rotary stage RT150up ID11 nanoscope Radial Error

#### **Rotating Sensitive Direction**

Reference Sphere: Single diam. = 25.4 mm
h = 242mm (from the top face)
5 forward of 5 full rotation (0 to 360 deg) - Meas. interval: 0,72 deg
continuous motion mode, after warm-up
(500 points / turn - averaging 200 points @ 50kHz)

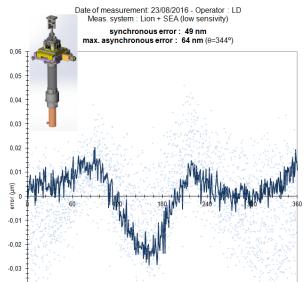
Date of measurement: 23/08/2016 - Operator : LD Meas. system : Lion + SEA min.synchronous error : 42 nm (φ=180°)



### Fixed Sensitive Direction Y Reference Sphere: Single diam. = 25.4 mm

h = 242mm (from the top face)

forward of 5 full rotation (0 to 360 deg) - Meas. interval: 0,72 deg continuous motion mode, after warm-up, without drift correct. (500 points / turn - averaging 200 points @ 50kHz)



## Asynchronous errors (repeatability) are larger than expected

Asynchronous\_5turns\_pos

Synchronous 5turns pos

-0,04

-0,05

➤ Mainly induced by an internal thermal drift in the RT150up (already visible during the characterization of the rotary stage standalone)

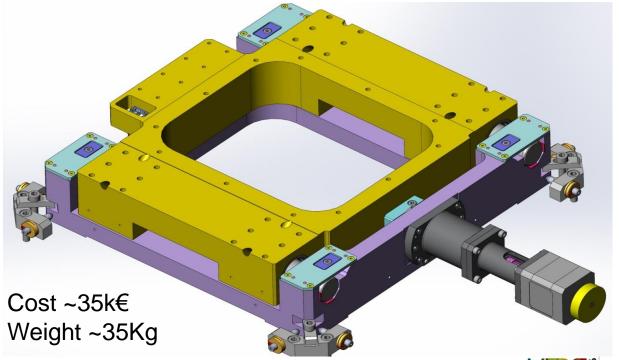




1 Div. = 2 nm

## IV. DTy – A high precision Linear Stage designed and assembled at ESRF

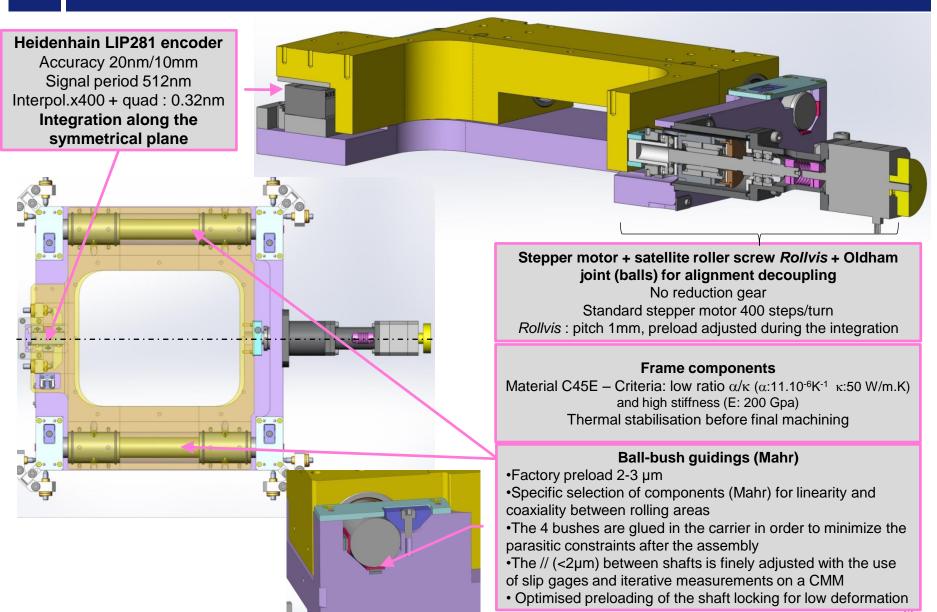
DTy stage	SPECIFICATIONS (@ POI H ~250mm)	
Stroke	10 mm	
Speed	1mm/s	
Carried load	37 kg	
Accuracy	3 μm	
Repeatability bidirectional (full stroke)	4 μm	
Repeatability bidirectional (stroke 100µm)	10 nm	
MIM	10 nm	
Straightnesses full stroke	10 μm	
Repeat. Straightnesses FS	1 μm	
Pitch error full stroke	5 μrad	
Repeat. pitch error FS	0.5 μrad	



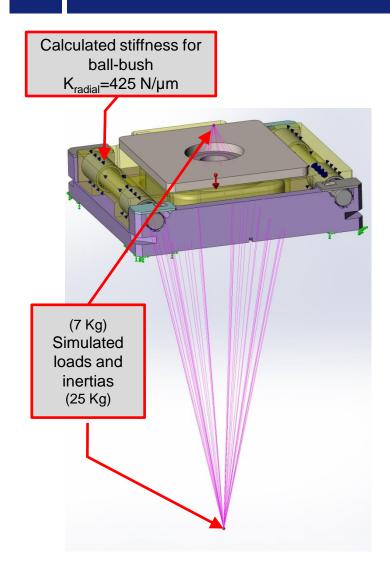


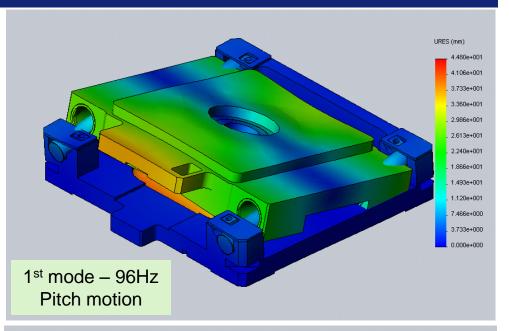


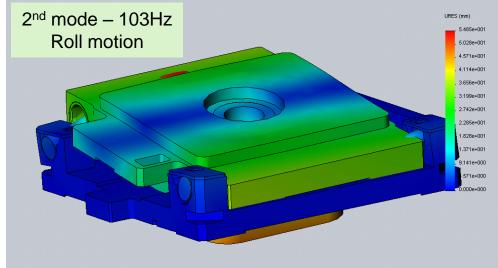
## IV. DTy Linear stage - Mechanical Design



## IV. DTy Linear stage – FEA calculations of Eigen frequencies





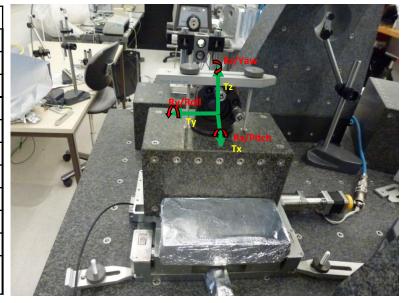


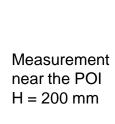


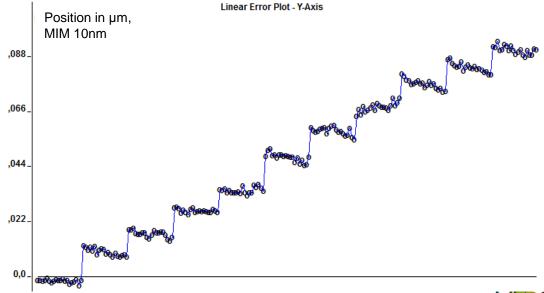


## IV. DTy Linear stage – Metrology characterisation

DTy stage	PEL meas.	SPECS
Accuracy & repeat. full stroke	263 nm / R 50nm	3μm R4
Accuracy & repeat. stroke 100μm	66 nm / R 27nm	3μm R10nm
MIM positive or negative	6 nm	10 nm
Straightness <b>horiz.</b> . full stroke	37 nm / R 33nm	10 μm R1
Straightness <b>horiz.</b> stroke 100µm	22 nm /R 20nm	/
Straightness <b>vertic.</b> full stroke	212 nm / R 115 nm	10μm R1
Straightness <b>vertic.</b> Stroke 100μm	27 nm / R 27nm	/
Pitch error <b>Ryx</b> full stroke	2.9 μrad / R 0.39 μrad	5μrad R0.5
Yaw error <b>Ryz</b> full stroke	4.5 μrad / R 0.33 μrad	/
Roll error <b>Ryy</b> full stroke	1.23 μrad / R 0.93 μrad	/
Accuracy & repeat full stroke @ Height 50mm and without load	47 nm /R 23nm	/







### V. CONCLUSION AND PERSPECTIVES

- ✓ An electrical slip-ring can pass sensitive signals
- ✓ The concept of integration used with the high precision rotary stage has
  no significant effect on the error motions
- ✓ A specific but simple linear stage can achieve a very high precision without any complex control systems
- √The RT150up stage can achieve very low motion errors
- X The thermal drifts of the rotary stage are not only along the linear axes X Improvements are possible :
  - reduction of heat sources
  - improvement of air-supplying distribution
  - thermal control of the RT150up frame
  - active compensation of error motions





## Thank you for your attention

## Any questions?

### **Acknowledgments**

**BL Team**: Jonathan Wright – Henri Gleyzolle – José-María Clément – Emmanuel Papillon

**AAM Group**: Yves Dabin – (ID16B end-station concept)

PDMU-PEL Metrology Lab: Hans-Peter van der Kleij – Léo Rousset

**PAMU Assembly Lab**: Giovanni Malandrino – Robin Grégoire – Rodolphe Grivelet **Subcontracted Design & Drafting**: Catherine Heyman (*Design & Mécanique*) – *SEI* 



